

1                   ABSTRACT OF THE DISCLOSURE

2       The present invention pertains to a more efficient system and method for forming

3       rectifying junction contacts in PIN alloy-semiconductor devices using photoelectrical and

4       chemical etching. The present invention provides a means of creating rectifying junction

5       contacts on alloy-semiconductor devices such as CdTe and CdZnTe, among others. In addition,

6       the present invention also provides a simple and low cost method for revealing wafer surface

7       morphology of alloy-semiconductors, thus providing an efficient and effective means for

8       selecting single grain semiconductor substrates. Further, the present invention provides

9       radiation detectors employing such alloy-semiconductor devices having improved rectifying

10      junctions as the detector element.

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